F-7904

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Manfred FRIEDRICH, et al.

Filed: September 4, 2003

For : SPUTTER IONS SOURCE

Mail Stop DD Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

Submitted herewith is an Information Disclosure Citation together with copies of references referred to therein.

Respectfully submitted,

Jordan and Hamburg LLP

C. Bruce Hamburg

Reg. No. 22,389

Attorney for Applicants

Jordan and Hamburg LLP 122 East 42nd Street New York, New York 10168 (212) 986-2340

F-7904

Form PTO-1449	U.S. Department of Commerce Patent and Trademark Office	Atty. Docket No.: F-7904		Serial No.: UNKNOWN			
(Rev. 7-80) 42-44F (F-49)		Applicant: Manfred FRIEDRICH, et al.					
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)		Filing Date: September 4, 2003		Group:			
	U.S. I	PATENT DOCUM	ENTS				
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	FOREIG	N PATENT DOC	JMENTS		<u> </u>		
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
Concise sta	ON KEY: * English Abstract. F Concise tement of relevance provided in specification of reference translated. O Englis	ication. S Cond	cise statement of re	levance	provided in	ort. IDS.	
	OTHER INFORMATION DISCLOSURE CITA						
	1993; Ion Sources For Accelerators In Materials Research; G.D. Alton; Nuclear Instruments and Methods in Physics Research; pgs. 221-288						
	4/2/93; Sputter Ion Source; High Volta	ge Engineering	Europa B.V.; pgs. 1	-18			
EXAMINER		DATE CONSIDERED					
EXAMINER: Init	tial if reference considered, whether or not c nd not considered. Include copy of this forn	itation is in confo	ormance with MPEP 60 nunication to applicant	9; Draw li t.	ne through ci	tation if	not in